

## TWIN – SC IV

### Implant Case Monitoring System

- based on thermal wafer inspection
- patented technology
- meeting today's needs in 300 mm fabs



- Modular design allowing customized system
- Fully automatic System with pattern recognition
- Lowest cost of ownership due to the use of laser diodes
- Factory automation (FAT), FTOO, FTOO+ available
- Short measurement time: <math>\pm 0.5\text{ min}</math>
- Patented double modulation technique
- Intuitive graphical user interface, based on Windows